

Contrôle Analytique K4000 Trace Gas Analyzer

SYSTEM CONFIGURATION

DATE: Sept,08,2005

S/N: 43004

Model:

K4000-230

Analysis Type:

Trace N2 in O2/Ar

Detector Type:

Plasma

Range set:

Range #1: 0-100ppm

Range #2: 0-1000ppm

Chromatographic Column:

Col #1: 8' washed molecular sieve, frit on both ends

Moisture Trap:

N/A

Chemical Trap:

O2 Trap

Gas conditioning Module (GCM):

N/A

Valves:

Injection: 1, 6 port diaphragm CAI G.C. Valve

Heartcut: 1, 6 port diaphragm CAI G.C. Valve

Sample Volume:

S.L.1: 91.0uL 6" tube ID 0.030"

Carrier Gas Type:

Argon

Carrier Gas Cylinder Pressure :
(with a gas purifier installed)

90 psig

Carrier Regulator PR1:

30 cc/min (FT2)

Default Sample Flow Set point:

25 sccm

Sample Pressure at the Sample Inlet:

10 psig to 15 psig

Total Carrier Flow Consumption:
(total carrier and valves actuating)

40 sccm

FLOW RESTRICTOR LIST

Restrictor R1:

Installed

Restrictor R2:

Installed

Restrictor R3:

Installed

Restrictor R4:

Installed

Restrictor R5:

Installed

Contrôle Analytique K4000 Trace Gas Analyzer

OPERATING PARAMETERS

DATE: Sept,08,2005

S/N: 43004

PEAK DATA

Peak Number	Name	AVR	Starting	Ending	Gain	Pol.	DET#	P.Pwr	Range2 Scale	Range1 fact	PRE AMP
1	N2	1	170.0	250.0	3	fol	1	65	1000	10x	1

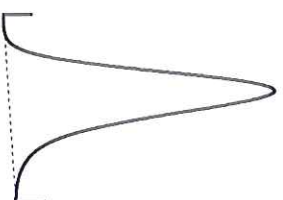
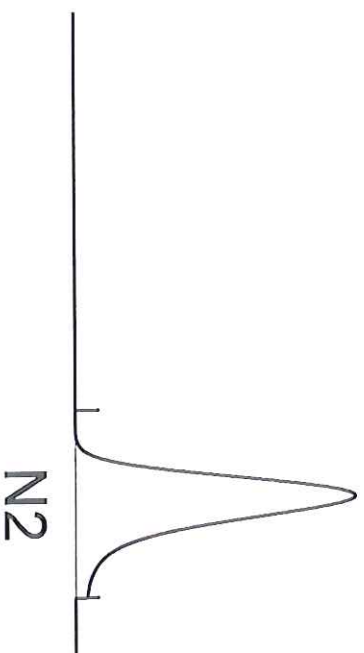
VALVE TIMING

	ON (sec)	OFF (sec)
V1	0	30
V2	0	120

OTHER PARAMETERS

Oven 1 temperature setpoint	50 °C
Carrier gas type	Argon
Cycle Time	350 sec
Cabinet Temperature Setpoint	40 °C

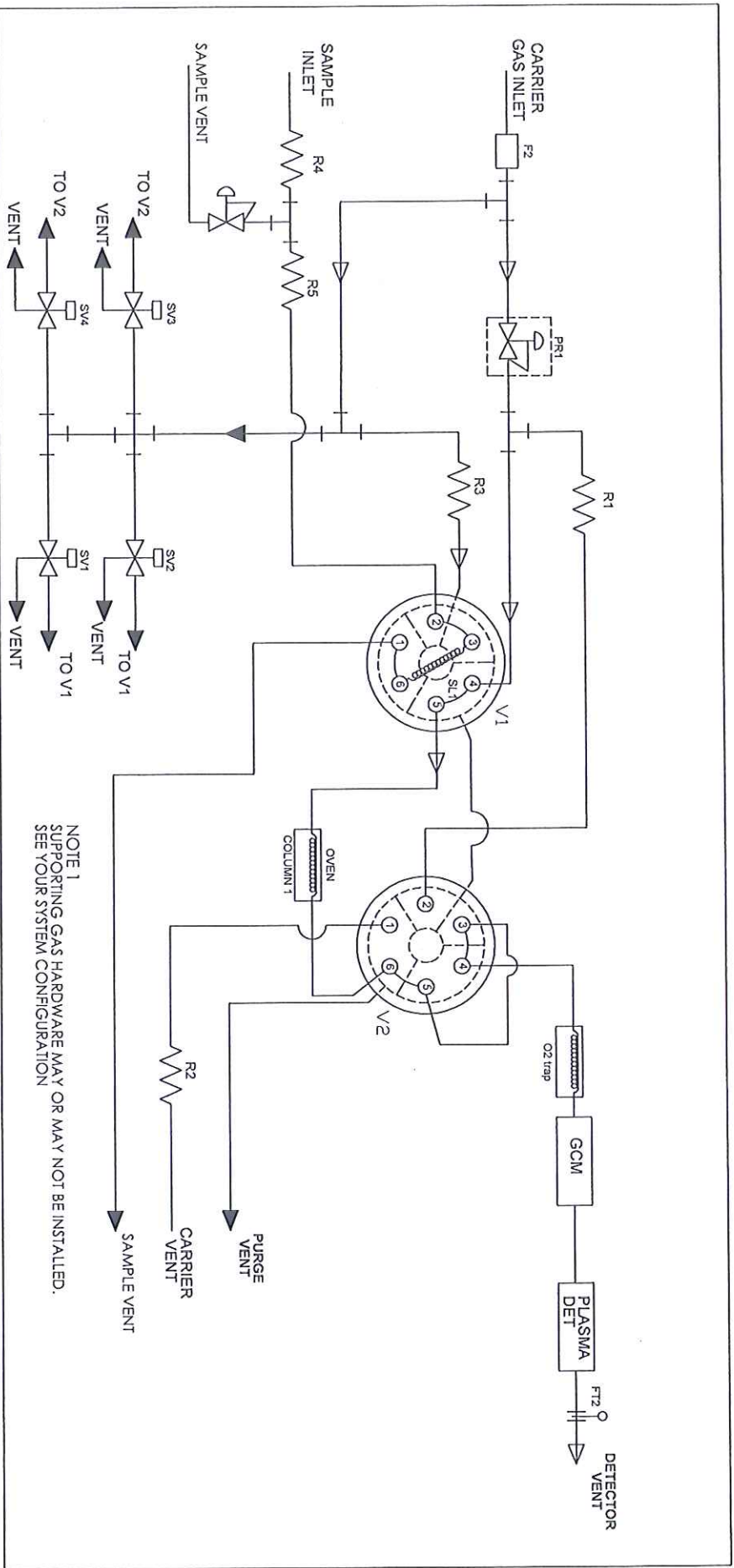
Cond. 1 Process Peaks



N2
100.00

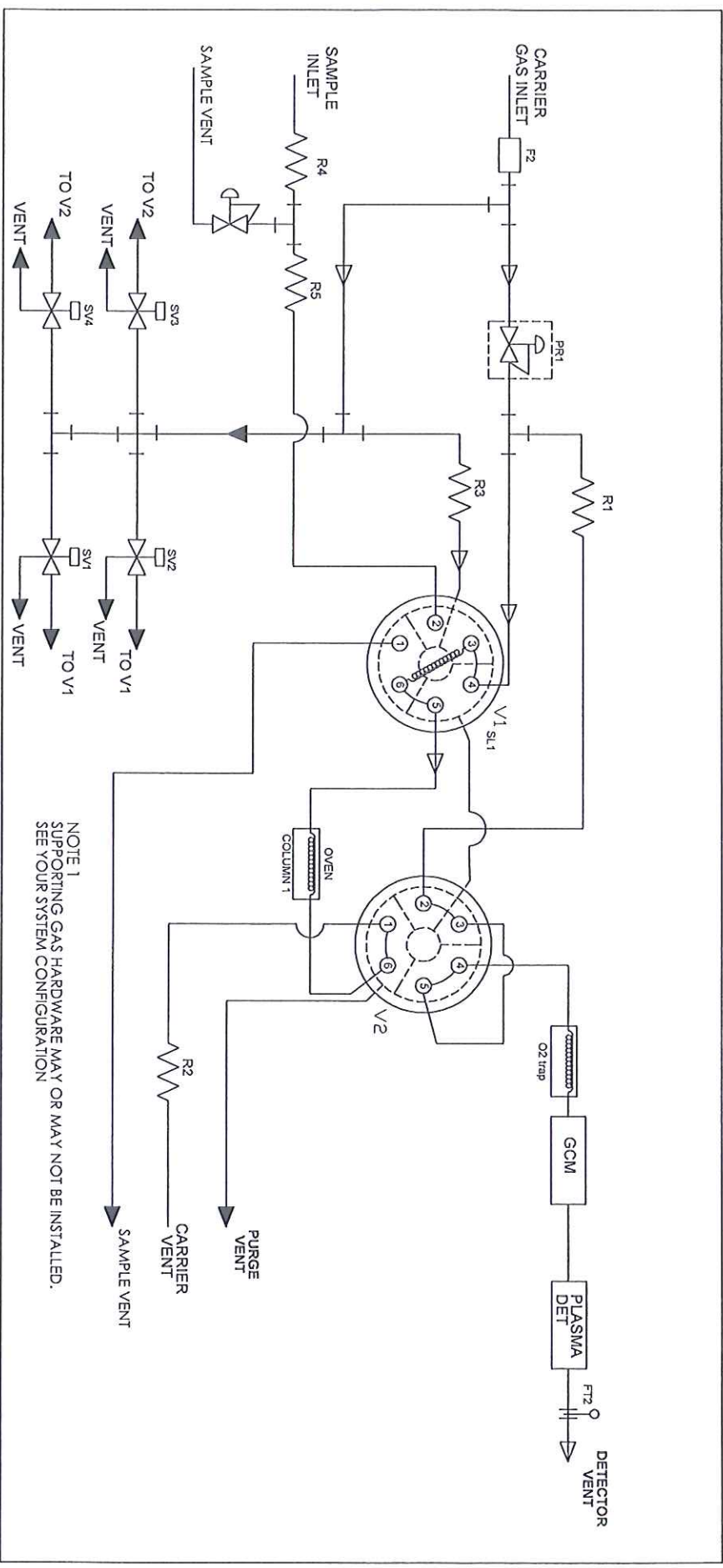
Oven 1
50

Sample	Carrier
25	30



OFF

- | | | | |
|------------|---|-----------------------|---|
| PR1 | PRESSURE REGULATOR FOR VALVE ACTUATING
(FACTORY SET) | SL1 | SAMPLING LOOP |
| PR2 | PRESSURE REGULATOR FOR VALVE ACTUATING
(FACTORY SET) | V1, V2 | CONTROL ANALYTIC STAINLESS STEEL DIAPHRAGM VALVE |
| F1, F2, F3 | 10 MICRONS PARTICLE FILTER
MOUNTED INSIDE BULKHEAD | FT1, FT2 | CARRIER FLOW SENSOR LOCATED ON I/O BOARD |
| GCM1 | GAS CONDITIONING MODULE | SV1, SV2,
SV3, SV4 | SOLENOID VALVE USED FOR DIAPHRAGM VALVE ACTUATING |
| R1, R2, R3 | FLOW RESTRICTORS | | |



ON			
PR1	PRESSURE REGULATOR FOR VALVE ACTUATING (FACTORY SET)	SL1	SAMPLING LOOP
PR2	PRESSURE REGULATOR FOR VALVE ACTUATING (FACTORY SET)	V1, V2	CONTROL ANALYTICAL STAINLESS STEEL DIAPHRAGM VALVE
F1, F2, F3	10 MICRONS PARTICLE FILTER MOUNTED INSIDE BULKHEAD	FT1, FT2	CARRIER FLOW SENSOR LOCATED ON I/O BOARD
GCM1	GAS CONDITIONING MODULE	SV1, SV2, SV3, SV4	SOLENOID VALVE USED FOR DIAPHRAGM VALVE ACTUATING
R1, R2, R3	FLOW RESTRICTORS		